



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Shuichi YABU

Application No.: 09/811,447

Filed: March 20, 2001

For: EXPOSURE APPARATUS, GAS REPLACING METHOD,  
AND METHOD OF MANUFACTURING A  
SEMICONDUCTOR DEVICE

)  
: Examiner: A. Mathews

)  
: Group Art Unit: 2851

)  
: December 12, 2002

Commissioner for Patents  
Washington, D.C. 20231

Sir:

Transmitted herewith is an Amendment in the above-identified application.

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DEC 16 2002  
TC 2800 MAIL ROOM

No additional fee is required.

The fee has been calculated as shown below:

CLAIMS AS AMENDED						
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL CLAIMS	51	MINUS	55	= 0	x \$9 \$18	\$ 0.00
INDEP. CLAIMS	16	MINUS	4	= 12	x \$42 \$84	\$1,008.00
Fee for Multiple Dependent claims \$140/\$280						—
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT						\$1,008.00

°Verified Statement claiming small entity status is enclosed, if not filed previously.

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A check in the amount of \$1,008.00 is enclosed including the additional claims fees.

Charge \$\_\_\_\_ to Deposit Account No. 06-1205. A duplicate of this sheet is enclosed.

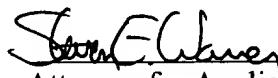
Any prior general authorization to charge an issue fee under 37 CFR 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 CFR 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate of this paper is enclosed.

A check in the amount of \$\_\_\_\_\_ to cover the fee for a \_\_\_\_\_ month extension is enclosed.

A check in the amount of \$\_\_\_\_ to cover the Information Disclosure Statement fee is enclosed.

Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address given below.

Respectfully submitted,

  
\_\_\_\_\_  
Attorney for Applicant  
Steven E. Warner  
Registration No. 33,326

FITZPATRICK, CELLA, HARPER & SCINTO  
30 Rockefeller Plaza  
New York, New York 10112-3801  
Facsimile: (212) 218-2200  
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The Commissioner for Patents  
Washington, D.C. 20231

#4/a  
12/17/02  
a/a

TC 2800 MAIL ROOM

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Sir:

In response to the Official Action dated September 12, 2002, please amend the above-identified application as follows:

IN THE SPECIFICATION:

Please amend the specification as follows:

Please substitute the paragraph beginning at page 2, line 5, and ending on page 3, line 3, with the following. A marked-up copy of this paragraph, showing the changes made thereto, is attached in Appendix A.

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A01 FC:1201  
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